

METHOD OF CORRECTING ELECTRON BEAMS AND ELECTRON BEAM ALIGNER

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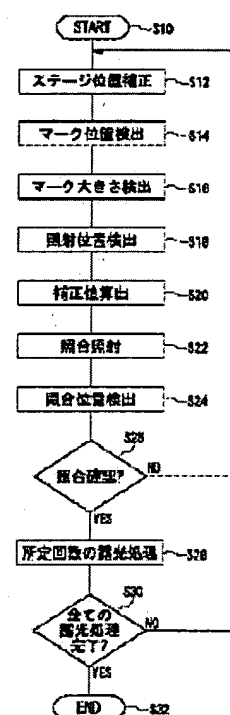
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A method for correcting the irradiating position of a plurality of electron beams using a plurality of marks comprising a step for detecting the positions of a plurality of marks relative to the irradiating position of one electron beam by irradiating the plurality of marks with one of the plurality of electron beams, a step for detecting the irradiating positions of a plurality of electron beams relative to one mark by irradiating one of the plurality of marks with the plurality of electron beams, and a step for calculating values for correcting the irradiating positions of the plurality of electron beams based on the detected positions of the plurality of marks and detected irradiating positions of the plurality of marks.



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